



[IST-1-506653-CA]

EUROSOI "Who is Who" Guide

Name of the organisation

Organization Legal name:	Kungl Tekniska Högskolan
Organization short name:	KTH
Internet homepage:	www.kth.se , www.ict.kth.se

Contact person

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Other Senior Researchers

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Experience and expertise fields

- Complete process line for 100 mm SOI MOSFETs
- Electrical device and materials characterisation
- Device simulation and modelling
- MEMS structures in SOI
- Nanoscaled Si/SiGe devices on SOI

Facilities and Equipment

The cleanroom facility at KTH is named the Electrum Laboratory (ELAB) and has a 1300 sqm cleanroom area. A decanometer silicon process line is serving the research projects. ELAB has a 100 mm wafer capability with some equipment having 200 mm wafer size. Among these an ASM2000 Si/SiGe epitaxy and Reactive etching can be mentioned. ELAB is equipped with both I-line and G-line stepper lithography and newly installed imprint lithography. In addition a MEMS fabrication line on bulk Si or SOI is available. ELAB also offers a III-V epitaxy for InP and GaAs based semiconductors, possible to integrate with novel silicon devices.



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Three last international research projects

IST-5th framework SIGMOS
IST 6th framework SINANO
IST 6th Cadres